



520.43079X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TANAKA et al

Serial No.: 10/648,231

Filed: August 27, 2003

For: System And Method For Evaluating A Semiconductor Device  
Pattern, Method For Controlling Process Of Forming A  
Semiconductor Device Pattern And Method For Monitoring  
A Semiconductor Device Manufacturing Process

Art Unit: 2825

Examiner: T. To

**AMENDMENT**

Mail Stop: Amendment (Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

November 20, 2006

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated May 19, 2006. The amendments are listed below and set forth on the following pages.

Amendments to the Specification;

Amendments to the Claims;

Amendments to the Drawings describing changes to drawing shown in the Appendix;

Remarks are included following the amendments; and

An Appendix including amended drawing figures is attached following the Remarks.